

**The Influence of High Temperature Steps on
Defect Etching and Dislocations:
Etch Pit Density Reduction in Multicrystalline Silicon**

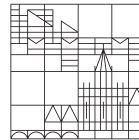
**Doctoral thesis for obtaining the
academic degree**

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at the

Universität
Konstanz



Mathematisch-Naturwissenschaftliche Sektion
Fachbereich Physik

Konstanz, 2020

Oral examination on November 23, 2020

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